

EXTENDED SENSOR BACK VOLUME

ABSTRACT OF THE DISCLOSURE

A microelectromechanical system (MEMS) transducer comprises a diaphragm and a back plate. The diaphragm and back plate are spaced apart and are made of semiconductor material using microelectronic fabrication techniques. The transducer also includes a pedestal comprising a cavity. The pedestal has a first end and a second end, and the back plate of the transducer is affixed to the first end, substantially covering the cavity. An extension member is affixed to the second end of the pedestal, enlarging the back volume of the transducer.

FIGURE 10